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PATENT PROPERTY ACHIEF MANAGEMENT OF THE PROPERTY OF THE PROP

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

RAEDER

Examiner:

Nguyen, D.

Serial No.:

09/383,876

Group Art Unit:

3723

Filed:

August 26, 1999

Docket No.:

AMDA.316PA

Title:

POLISHING UNIFORMITY VIA PAD CONDITIONING

CERTIFICATE UNDER 37 CFR 1.8: The undersigned hereby certifies that this communication is being deposited in the United States Postal Service, as first class mail, in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231, on January 19, 2001.

Eynda J. Baue

OFFICE ACTION RESPONSE

Assistant Commissioner for Patents Washington, D.C. 20231

JAN 25 2001

Sir:

In response to the Office Action dated October 19, 2000, please amend the aboveidentified patent application as follows:

In The Figures

Please replace Fig. 2 with the attached replacement sheet to show the changes reflected thereon in red ink.

In The Specification

Please amend the specification as follows:

Page 8, line 3, after "present invention.", insert FIG. 2 shown the wafer carrier 130 (along with wafer 135) misaligned over and with respect to the center of the pad 140a. --

Page 9, line 17, please delete "A" and "B".

Page 9, lines 16-19, after each occurrence of "pad", insert -- 140a --, and after each occurrence of "edge", please insert -- 230 --.